

In situ grown $\text{YBa}_2\text{Cu}_3\text{O}_{7-\delta}$ thin films from single-target magnetron sputtering

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Using single-target off-axis sputter deposition, high quality superconducting films of $\text{YBa}_2\text{Cu}_3\text{O}_{7-\delta}$ were made *in situ*. These films have properties which are distinctly different from those of bulk ceramics and of post-deposition annealed films. Their superconducting resistive transitions remain sharp regardless of the value of T_c between 75 and 86 K. Normal-state conductivities are as high or higher than the best single crystals. Critical current densities are as high as $6 \times 10^7 \text{ A/cm}^2$ at 4.2 K. $T_c(R=0)$ falls off with film thickness down to 10 K for 35–40 Å films. All of the above properties are relatively insensitive to compositional variation. The results can be explained if the *in situ* growth results in well-formed CuO_2 planes with defects occurring elsewhere.

In this letter, we report results on YBaCuO films grown *in situ* using an off-axis single-target magnetron sputtering technique that reproducibly exhibits novel physical and materials properties.

Stoichiometric targets were prepared from "freeze-dried" powders using the method developed by Johnson *et al.*¹ The depositions were performed in a high oxygen partial pressure environment. Substrates were placed on the side of a planar magnetron gun² to avoid backsputtering damage from negative oxygen ions as shown in Fig. 1. The sputtering atmosphere consisted of, in most cases, 10 mTorr O_2 (or N_2O) and 40 mTorr Ar. The rf power (125 W) on the sputter gun generated a self-bias of -50 to -75 V and gave a deposition rate of about 0.5 Å/s . The substrate temperature during deposition was measured by a thermocouple embedded in a block to which the substrates were clamped. The block temperature was held at $600\text{--}700 \text{ °C}$ during film growth. Film thicknesses varied from 35 to 4000 Å. Substrate materials included $\text{MgO}(100)$, $\text{SrTiO}_3(100)$ and (110) , $\text{LaAlO}_3(100)$, yttria-stabilized zirconia, and *R*-plane sapphire. After deposition, the chamber was immediately vented to 600 Torr of oxygen.

The compositions of the films were measured with an electron microprobe; the results were verified in some cases by inductively coupled plasma spectroscopy or Rutherford backscattering. A small phase spread was found over an area of 1 in.² from which reproducibly good films could be obtained. In a typical run using a target of composition $\text{Y}_{17.7}\text{Ba}_{32.9}\text{Cu}_{49.4}$, the composition of the films at the extreme positions (Fig. 1) varied from $\text{Y}_{18.6}\text{Ba}_{32.8}\text{Cu}_{48.5}$ to $\text{Y}_{16.9}\text{Ba}_{33.1}\text{Cu}_{50.0}$, illustrating the 1:1 correspondence between target and film composition. In what follows we assume the films to have the composition of the two targets (1:2:3 and 1:2:3.5) from which they were fabricated. As will

be shown below, the physical properties we discuss here are not very sensitive to the composition of the *in situ* grown films.

Characteristics of representative films are given in Table I. Even though transition temperatures at zero resistivity (T_{c0}) are somewhat lower than those of bulk materials, the transition widths ΔT (defined by the temperature between 90% of the normal state resistivity near T_c and the temperature at zero resistivity) were sharp; $\Delta T \sim 3\text{--}1 \text{ K}$ for T_c 's varying from 75–86 K. Figure 2 shows representative ρ vs T transitions of films grown on $\text{MgO}(100)$. The inset shows the narrow transition width of a high T_c film. The normal-state resistivity of the good film is at least as low as that of the single crystal.³ From the x-ray data discussed below, it is certain that this is not due to the high conductivity of the 2-4-8 phase.⁴ Even for films as thin as 35 Å, the superconducting transition is still completed at 10 K [Fig. 2(d), dotted line], which implies a very sharp film-substrate interface with little interdiffusion. Sharp interfaces have also been seen on thicker films by cross-sectional transmission electron microscopy (TEM). The superconducting transition of the 35 Å film went away after four months vacuum storage, but partially recovers upon a 10 min, 400 °C oxygen anneal. This behavior seems to be consistent with the loss of surface oxygen in vacuum as has been seen by some surface analysis work.

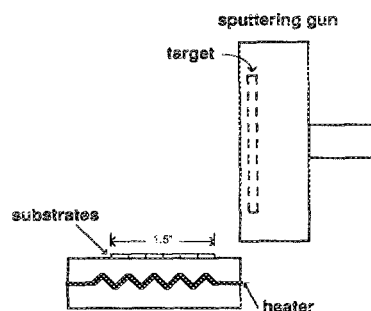


FIG. 1. Sputtering system geometry.

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TABLE I. Properties of films grown with *in situ* off-axis magnetron sputtering.

Comp.	Substrate	$T_{\text{sub}}/P_{\text{O}_2}$	Texture	T_{c0} (K)	ΔT_c (K)	J_c (A/cm ²)
1:2:3	MgO (100)	660 °C/10 mT	<i>c</i>	85	<1	6×10^7
1:2:3	MgO (100)	660 °C/10 mT	<i>c + a</i>	82	<1	2×10^7
1:2:3.5	MgO (100)	630 °C/10 mT	<i>c + a</i>	82	1	9×10^6
1:2:3	SrTiO ₃ (100)	700 °C/100 mT	<i>c</i>	86	<1	...
1:2:3.5	SrTiO ₃ (100)	660 °C/10 mT	<i>c + a</i>	85	3	5×10^6
1:2:3.5	LaAlO ₃ (100)	660 °C/10 mT	<i>c + a</i>	84	3	4×10^6
1:2:3	YSZ (100)	660 °C/60 mT	<i>c</i>	84	1	5×10^6
1:2:3	Al ₂ O ₃ (1102)	700 °C/100 mT	<i>c</i>	87	1.5	2×10^6

Structural studies show that films less than 4000 Å thick on MgO(100) are purely *c*-axis oriented and epitaxially aligned in the substrate plane. The surfaces are very smooth; no features could be detected within the ~200 Å resolution of the scanning electron microscopy (SEM). Figure 3 shows a typical x-ray diffraction scan normal to a stoichiometric *c*-axis film's surface. Impurity peaks were absent in 1:2:3 samples. The high phase purity of one of such film was confirmed using a slow scan and a thin-film diffractometer. An ω rocking on the YBa₂Cu₃O₇(005) peak was found to be only 0.2° of full width at half maximum (FWHM). More quantitative studies of the x-ray data revealed an interesting relationship between the *c*-lattice parameter and the transition temperature.

In Fig. 4(a), the transition temperatures (T_{c0}) of films grown at various deposition temperatures and oxygen partial pressures are plotted against the *c*-lattice parameters, together with similar data obtained from studies on bulk ceramics.^{5,6} The *c*-lattice parameter increased with decreasing substrate temperature and oxygen pressure. In our experience, the T_{c0} corresponds well with the onset of T_c measured by magnetization. Accordingly, in Fig. 4 we used onset for the bulk T_c 's. It is clear from Fig. 4(a) that the T_c of our *in situ* grown thin film has a much weaker dependence on the *c*-lattice parameter, and that even our best as-grown films have longer *c*-lattice parameters than those of bulk ceramics or post-annealed films. Also, in films with mixed *a* and *c* orientations, the *a*-lattice parameter was measured. It was

confirmed by off-axis x-ray diffraction that the *c*-lattice parameter of *a*-axis grains is equal to the *c*-lattice parameter of *c*-axis grains on two films that contain a mixture of *a + c* oriented grains. That result rules out the possibility that differential thermal expansion between the films and the substrates makes a large contribution to the difference in the *c*-lattice parameters. The relation between the *c*-lattice parameter and *a*-lattice parameter is shown in Fig. 4(b). Unlike the bulk ceramics where an expansion of the *c*-lattice parameter is accompanied by a similar expansion of the *a* axis, our *in situ* films tend to have a rather constant *a*-lattice parameter, even when the *c*-lattice parameter varies.

The expansion of the *c*-lattice parameter was found not to be due to oxygen deficiency. A series of annealing experiments was conducted. Anneals at 650 °C in oxygen caused no significant change in lattice parameters and T_c , suggesting that the origin of the expanded *c*-lattice parameter and the rather insensitive dependence of T_c on the *c*-lattice parameter is not simply due to oxygen deficiencies. Anneals at 850 °C in oxygen, however, did increase the T_c up to above 87 K and did shrink to the 11.68 Å *c*-lattice parameter characteristic of bulk YBa₂Cu₃O₇. Such temperatures are high enough to cause recrystallization of the films^{7,8} and thus it is not surprising that the films become more like bulk material and post-annealed films. The 400 °C anneals in 10 mTorr of oxygen show depletion of oxygen from films; T_c degraded to around 30 K, and the *c*-lattice parameter and *a*-lattice parameter expanded significantly, closely approaching that of

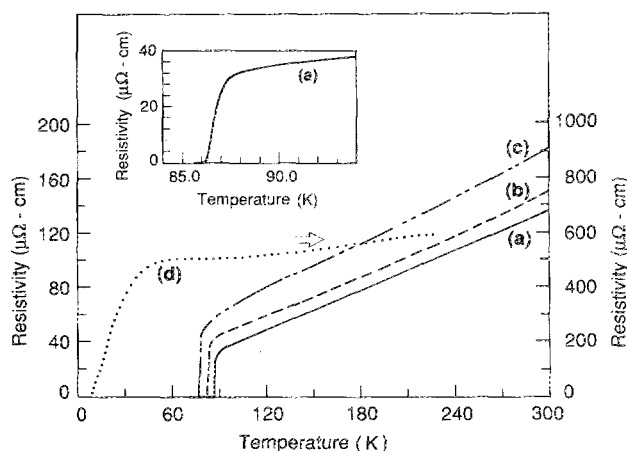


FIG. 2. Typical resistive transitions for films on MgO. (a) $T_{c0} = 86.2$ K, (b) $T_{c0} = 82.5$ K, (c) $T_{c0} = 79$ K. Lower T_c films are grown at lower temperature and oxygen pressure. (d) The resistance transition for 35-Å-thick film. ($T_{c0} = 10$ K).

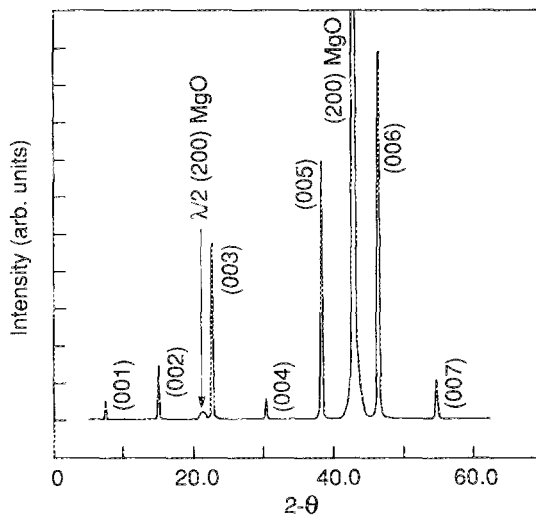


FIG. 3. X-ray diffraction pattern using Cu $K\alpha$ source showing clear *c*-axis orientation.

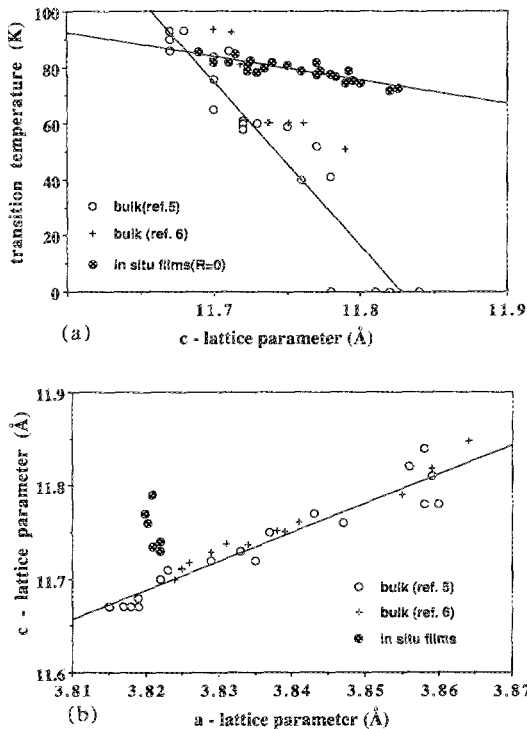


FIG. 4. (a) Transition temperatures vs c -lattice parameters for *in situ* film (closed circle) compared with the bulk ceramic's (open circles,⁵ crosses⁶). (b) c -lattice parameters vs a -lattice parameters of thin and bulk ceramic films grown *in situ*.^{5,6}

the bulk values for the same T_c (Fig. 4). Subsequent 400 °C anneals of the same films in 1 atm oxygen returned T_c , and the c -, and a -lattice parameters to their original values. Reversible entry and exit of oxygen in bulk material is well known to be caused by oxygen movement on the chain sites; the same evidence occurs in the *in situ* films. It is evident that depletion of oxygen content from *in situ* samples is not the same degradation as is caused by nonoptimal *in situ* growth [Fig. 4(a)].

The critical currents of these films were calculated from magnetization data using Bean's formula, which for thin films with large demagnetization factors could be applied down to quite low fields (~ 1 kG). The zero field current density was then estimated by extrapolation. Typical values of critical current densities for our 1:2:3 films are around $(2-6) \times 10^7$ A/cm² at 4.2 K. In general, the critical currents have a weaker field dependence than do post-annealed films, dropping only by a factor of 2 from zero to 1.5 T, rather than > 3 for post-annealed films.⁷ Two tests were made with patterned films. The critical current for a 250- μ m-wide, wet-etched film exceeded the limit of the measuring probe, 1×10^5 A/cm² at 1.3 K below T_c . In an experiment being carried out at Stanford with S. Tahara, a film patterned to make a 1- μ m-wide bridge by ion milling T_c was degraded by 10 K, however, the transport critical current at 4.2 K was 2×10^7 A/cm².

T_c and critical current densities of post-annealed films are very sensitive to composition. A 10% deviation from stoichiometry seriously degrades the critical current density and T_c .⁸ In contrast, the superconducting properties of the

in situ grown films were found to be quite insensitive to overall cation compositional variations. As can be seen in Table I, off composition 1:2:3.5 films have only slightly poorer critical current densities, 9×10^6 A/cm² at zero field. Furthermore, the critical currents remain relatively insensitive to field.

In conclusion, high quality epitaxial YBaCuO films, which have a high degree of orientation, smooth surfaces, and high critical current densities, have been grown *in situ* via magnetron sputtering at intermediate pressures and relatively low substrate temperatures. The transition temperatures of the best films are slightly lower than bulk values and the c -axis lattice parameters are longer. These properties are not due to oxygen deficiencies at the chain sites. It is rather possible that the low-temperature growth of thin films introduces disorder or defects. Such defects on the oxygen "bridge" sites, for example, could account for the increased c -lattice parameter and might act as additional pinning sites. An overall more uniform distribution of defects resulting from the low-temperature growth might also account for the unusual dependence of T_c upon lattice parameters. The large normal-state conductivity, high critical current density, and the constant near-single-crystal value of the a -axis support the idea that the CuO₂ planes are left intact. The fact that ultrathin superconducting films below 50 Å can be grown sets a limit on substrate-film interaction.

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